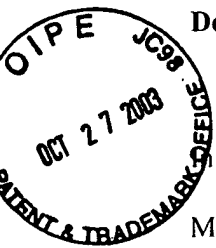


B



Docket No.: 1268-093A

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Continuation of

Moshe FINAROV

U.S. Patent Application No. 09/626,793

Filed: July 26, 2000

: ATTN: BOX ISSUE FEE

: Confirmation No. 8657

: Group Art Unit: 2851

: Allowed: September 29, 2003

: Examiner: David B. Esplin

For: APPARATUS FOR INTEGRATED MONITORING OF WAFERS AND FOR PROCESS CONTROL IN THE SEMICONDUCTOR MANUFACTURING AND A METHOD FOR USE THEREOF

AMENDMENT UNDER 37 CFR 1.312

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This paper is submitted to include a specific reference to a prior-filed application in the first sentence of the specification. In view of this specific reference, issuance of a corrected filing receipt is respectfully requested. Note that the time period of 37 CFR 1.78(a) does not apply because the instant application was filed before November 29, 2000. See 37 CFR 1.78(a)(2)(ii)(B).

Under the provisions of 37 CFR 1.312, please enter the following amendment:

AMENDMENTS TO THE SPECIFICATION begin on page 2 of this paper.